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AF

Docket No.: 9323.051.00-US  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:  
In Kwon JEONG

Customer No.: 30827

Application No.: 09/931,695 ✓

Confirmation No.: 3412

Filed: August 16, 2001

Art Unit: 1753

For: SYSTEM AND METHOD FOR PROCESSING  
SEMICONDUCTOR WAFERS USING  
DIFFERENT WAFER PROCESSES

Examiner: Brian L. Mutschler

MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Sir:

In response to the Final Office Action dated August 19, 2004, please amend the patent application identified above as follows:

**INTRODUCTORY COMMENTS**

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 10 of this paper.

Do not  
enter.  
B 10/18/04